



## EBA & EBA/RF & DZ Series Batch Type Vacuum Coating System

### System Summary

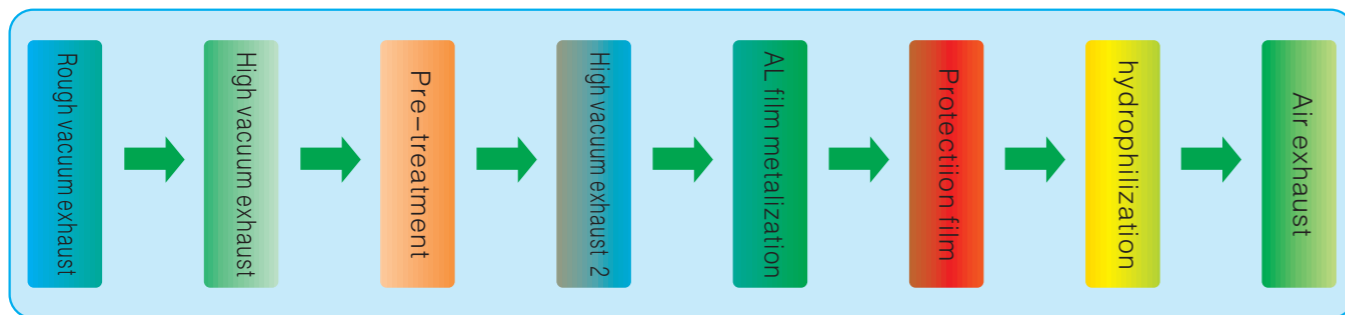
- This equipment, employing vertical double door open mechanism is applied to deposit Al reflection film and superposite SIOx protection film on the reflection board of automotive lighting parts, and decoration.

### Appliance

- Perform film metaliation on the PC,BMC,ABS metal materials;

### Features

- Adopt vertical double door open mechanism, tight compact;
- Each door is equipped with a set of 6-axis/8-axis self-revolution mechanism, a set of epevaporation power, a set of superposition power. One door is performing film metalization, the other door can unload test part,install Al material.
- PLC control and touch screen interface, can realize full-automatic operation, easy operation.
- Advanced production process control program, high quality of film metalization.



### Technical Parameters

Item	EBA-2000C	EBA-2000HC
1. Vacuum room & door	Vertical cylindrical type, double door	
2. Internal cavity size	Φ 1600mm*H1500mm	Φ 1600mm*H1200mm
3. Cycle time (unloaded)	15min/per cycle	
4. Height of effective film deposition area	H1200mm	H1700mm
5. Self-resolution mechanism	6-axis/8-axis	
6. Metallization method	Resistance heating	
7. Superpositon method	DC plasma polymerization	
8. Gas exhaust system	able to assemble domestic pump or imported pump	
9. Cold trap (optional)	America polycold	
10. Vacuum gauge	able to assemble domestic gauge or imported gauge	
11.Power	about 105KVA	about 110KVA
12. Cooling water	about 120L/min	
13. Space layout	about W6.9m*D6.2m*H3.0m	about 6.9m*D6.9*H3.2m

Item	EBA-1200HC/RF	EBA-2000C/RF	EBA-2000HC/RF
1. Vacuum room & door	Vertical cylindrical type, double door		
2. Internal cavity size	Φ 1200mm × H1300mm	Φ 1600mm × H1500mm	Φ 1600mm × H2000mm
3. Cycle time (unloaded)	12min/per cycle	15min/per cycle	
4. Height of effective film deposition area	H1000mm	H1200mm	H1700mm
5. Self-resolution mechanism	5-axis	6-axis/8-axis	
6. Metallization method	Resistance heating		
7. Superpositon method	RF plasma polymerization		
8. Gas exhaust system	able to assemble domestic pump or imported pump		
9. Cold trap (optional)	America polycold		
10. Vacuum gauge	able to assemble domestic gauge or imported		
11.Power	about 96KVA		about 101KVA
12. Cooling water	about 120L/min		
13. Space layout	about W4.9m × D5.8m × H3.0m	about W 6.9m × D6.2m × 2.9m	about W 6.9m × D6.9 × 3.2m

DZ-850	
Item	Technical Parameters
1.Vacuum room & door	Vertical cylindrical type, double door
2. Internal cavity size	Φ940mm × H1900mm
3. Cycle time (unloaded)	420S/per cycle
4. Effective film deposition area	Φ850mm × H1700mm
5. Self-resolution mechanism	1-axis( Max.self-revolution diameter 850mm)
6. Metallization method	Resistance heating
7. Superpositon method	RF plasma polymerization
8. Gas exhaust system	able to assemble domestic pump or imported pump
9. Cold trap (optional)	America polycold
10. Vacuum gauge	able to assemble domestic gauge or imported gauge
11.Space layout	about W4.2m × D6.2m × H2.9m
12. Power	about 88KVA
13. Cooling water	about 111L/min